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APPLICANT: SHIN ETSU CHEM CO LTD;

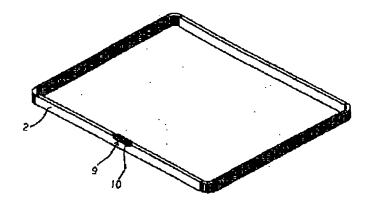
INVENTOR: NAGATA AKIHIKO;

INT.CL.

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TITLE

PELLICLE AND ITS PRODUCTION



ABSTRACT: PROBLEM TO BE SOLVED: To make catchable fine foreign matter (dust) while ensuring gas permeability by providing a pellicle frame having a groove-shaped notch containing a disposed filter in the upper end face and/or the lower end face.

> SOLUTION: A groove-shaped notch 9 is formed in the upper end face and/or the lower end face of a pellicle frame 2 and a filter 10 is disposed in the notch 9 to obtain a ventilation mechanism. In the production of a pellicle, the size of the notch (groove) 9 can be relatively freely varied. Since the filter 10 is not disposed from the outside of the notch 9 but disposed in the notch 9, foreign matter existing on the inside of the notch 9 does not enter the pellicle. The material of the filter 10 may be a resin such as polytetrafluoroethylene(PTFE) or nylon 66, a metal such as 316L stainless steel or ceramics such as alumina or aluminum nitride but any material may be used if it is porous and has gas permeability.

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